

RESPONSE UNDER 37 CFR 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
Kazunori IWAMOTO et al.	:	Examiner: H. Nguyen
Application No.: 09/866,600	:	Group Art Unit: 2851
Filed: May 30, 2001	:	Confirmation No.: 4961
For: STAGE APPARATUS WHICH SUPPORTS	:	August 6, 2004
INTERFEROMETER, STAGE POSITION MEASUREMENT METHOD, PROJECTION	:)	
EXPOSURE APPARATUS, PROJECTION EXPOSURE APPARATUS MAINTENANCE	:)	
METHOD, SEMICONDUCTOR DEVICE MANUFACTURING METHOD, AND	:	
SEMICONDUCTOR MANUFACTURING FACTORY	:	

Mail Stop AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

₁∳ Sir:

In response to the final Official Action dated May 7, 2004, please amend the above-

identified application as follows, pursuant to 37 C.F.R. § 1.116: